

FIG. 1

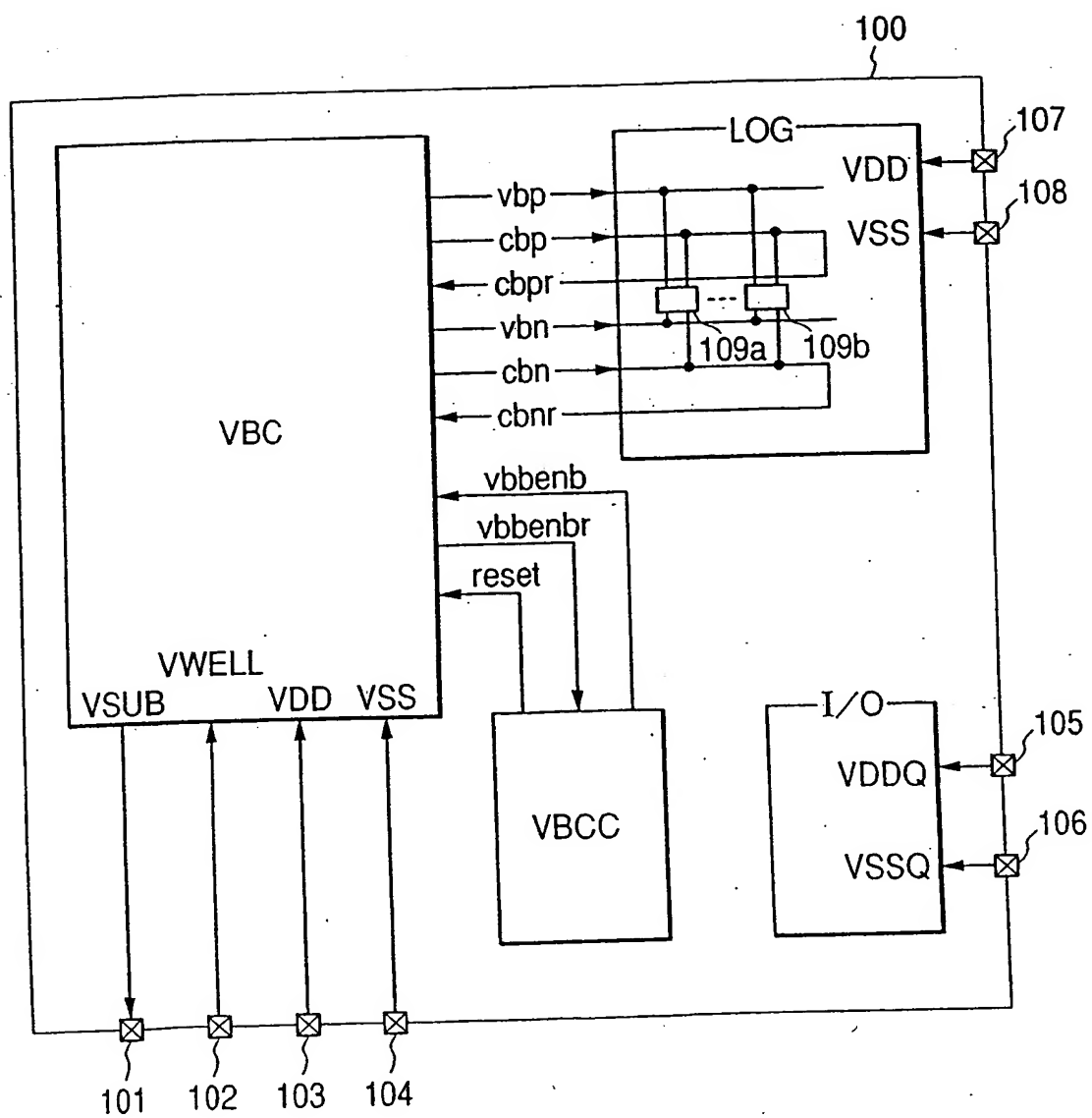


FIG. 2

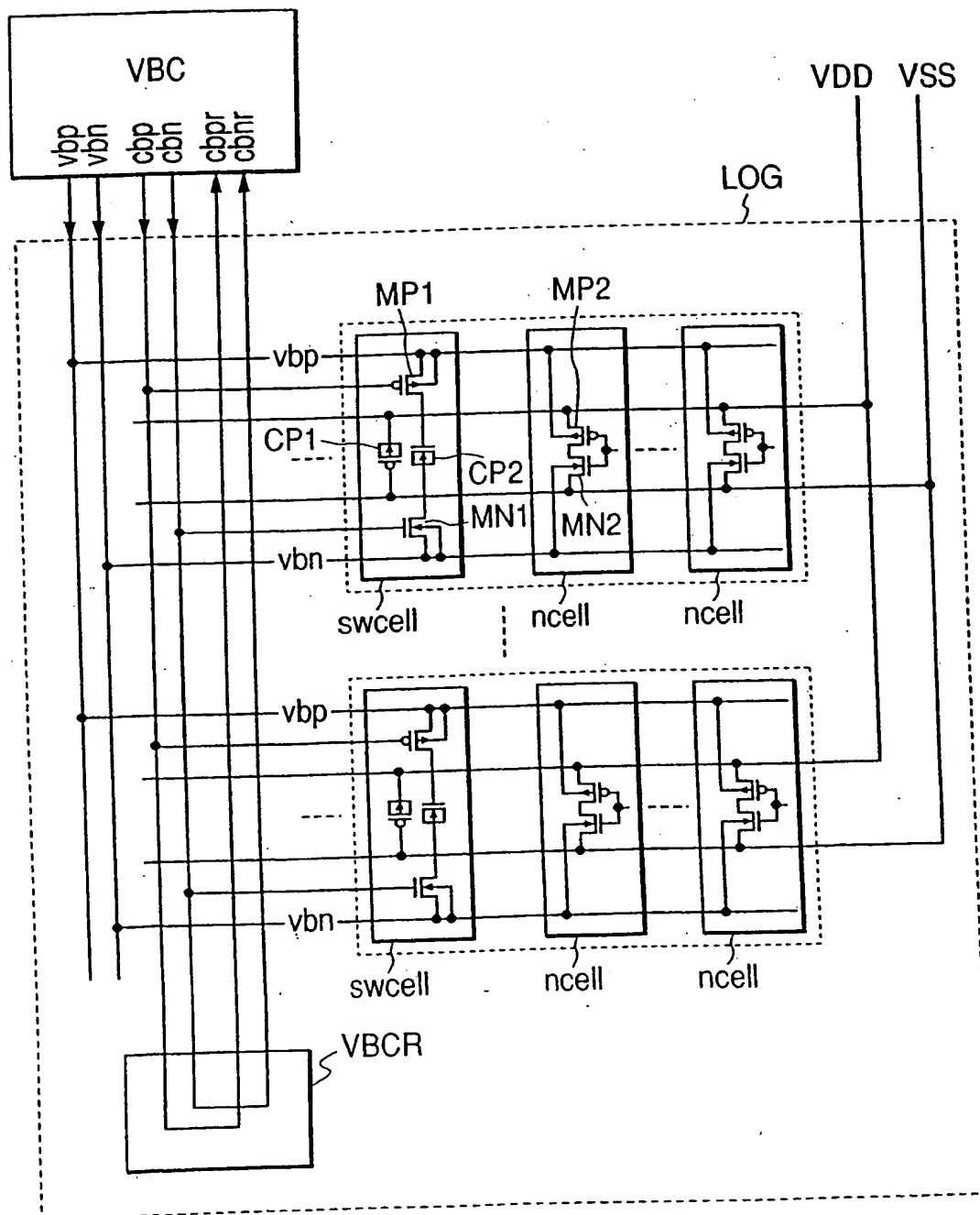
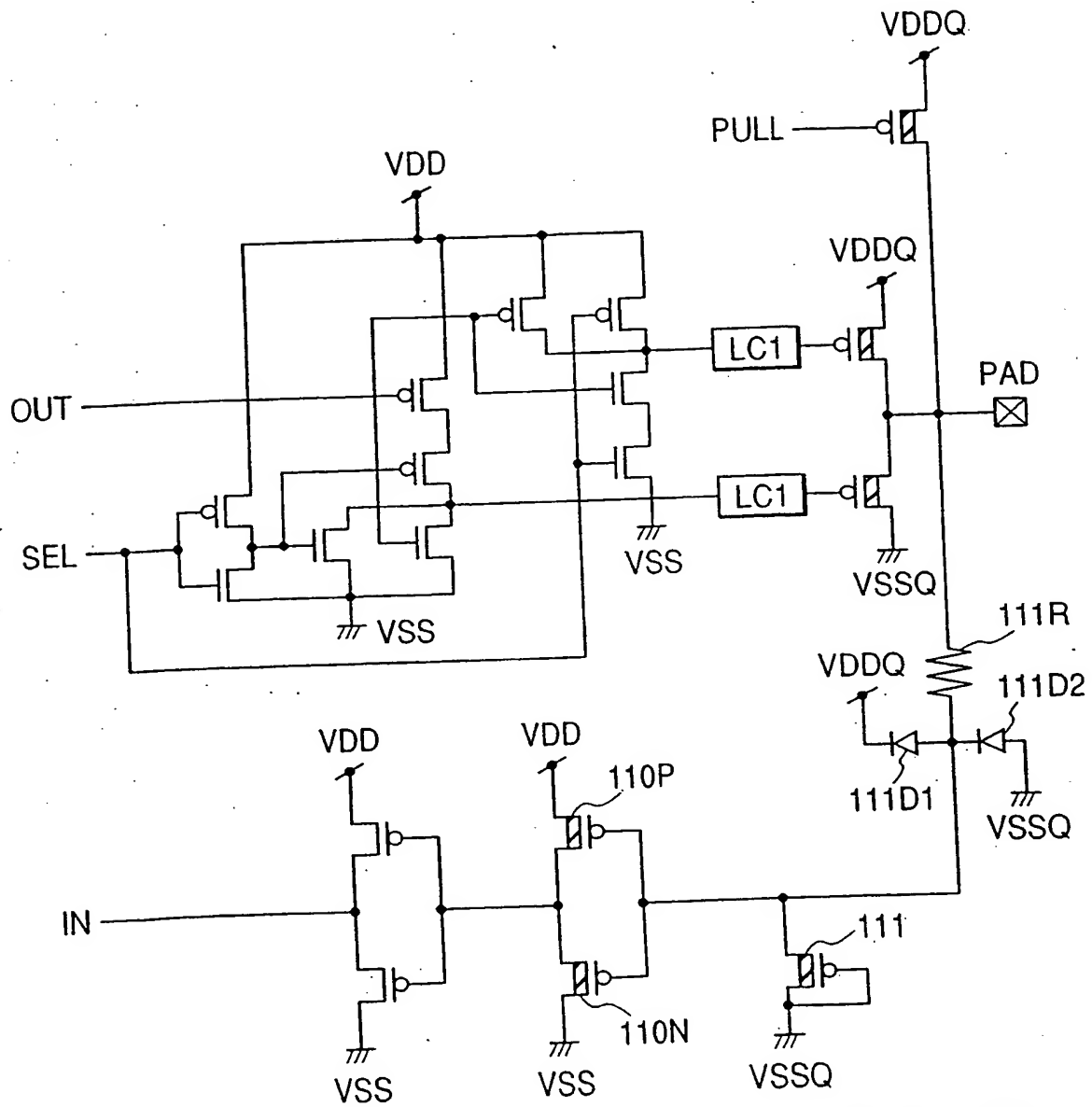
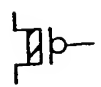



FIG. 3



  = THICK OXIDIZATION FILM TRANSISTOR, HIGH THRESHOLD LEVEL, WITHOUT  $V_{BB}$  CONTROL

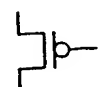

  = THIN OXIDIZATION FILM TRANSISTOR, LOW THRESHOLD LEVEL, WITH  $V_{BB}$  CONTROL

FIG. 4

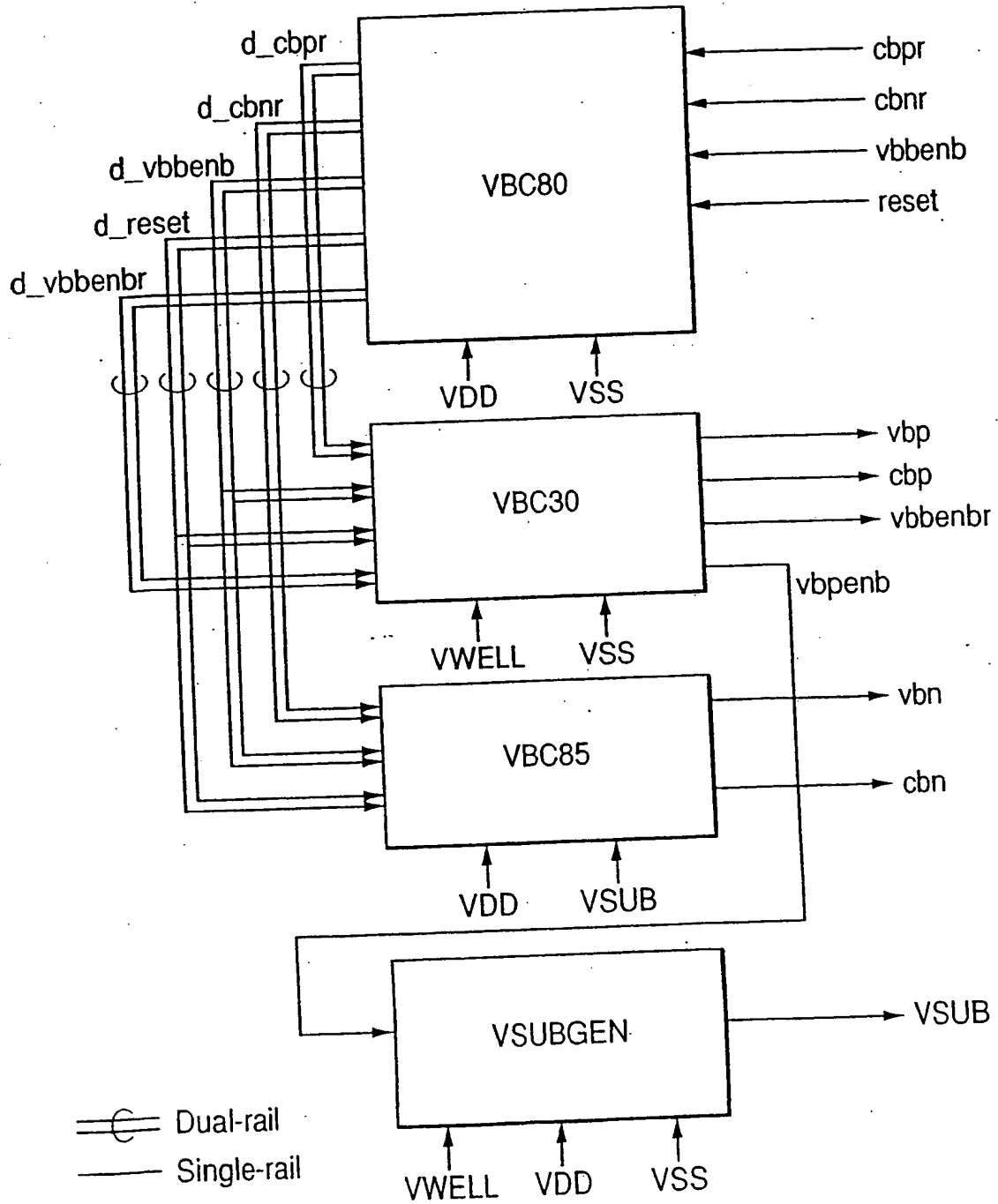
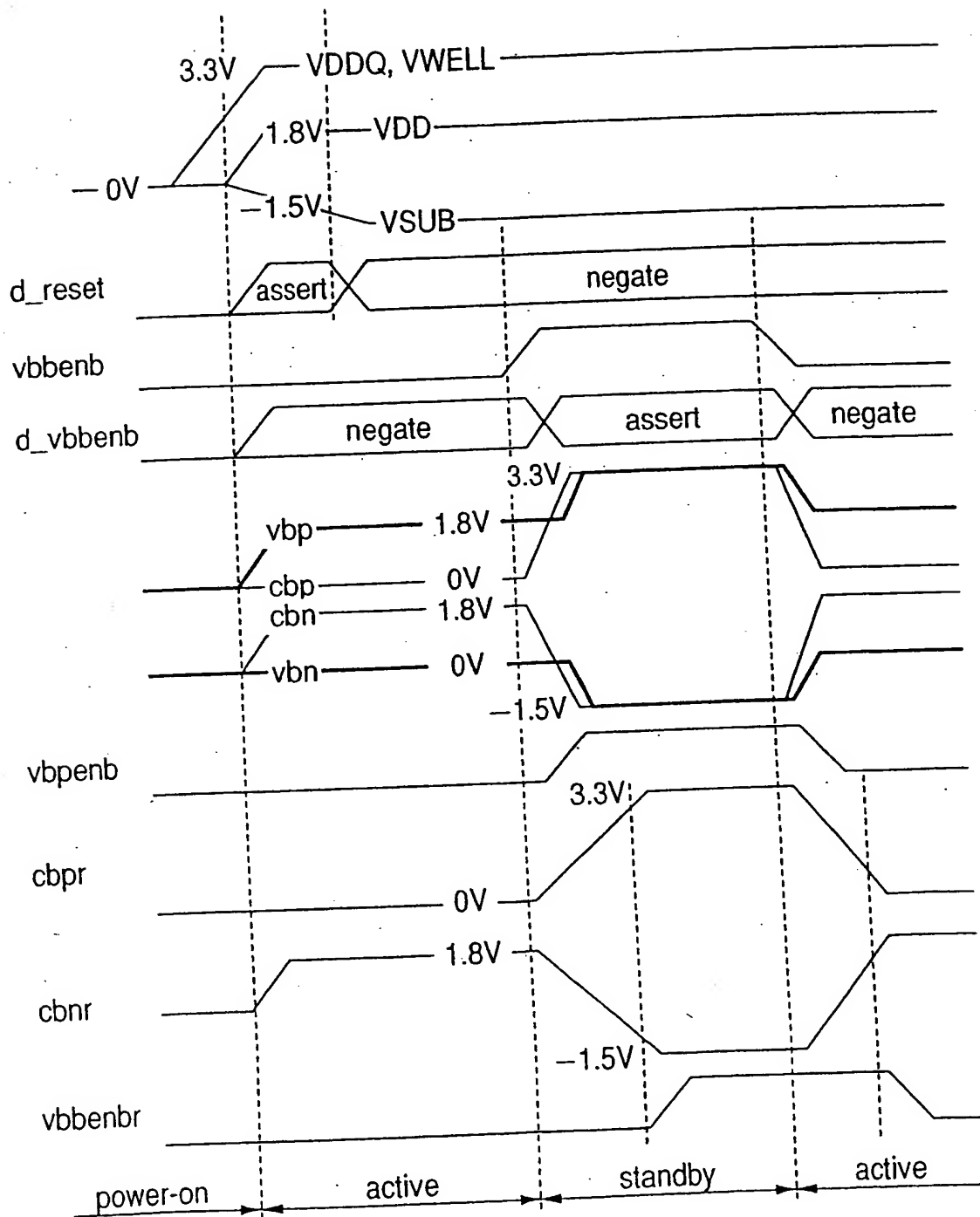
VBC

FIG. 5



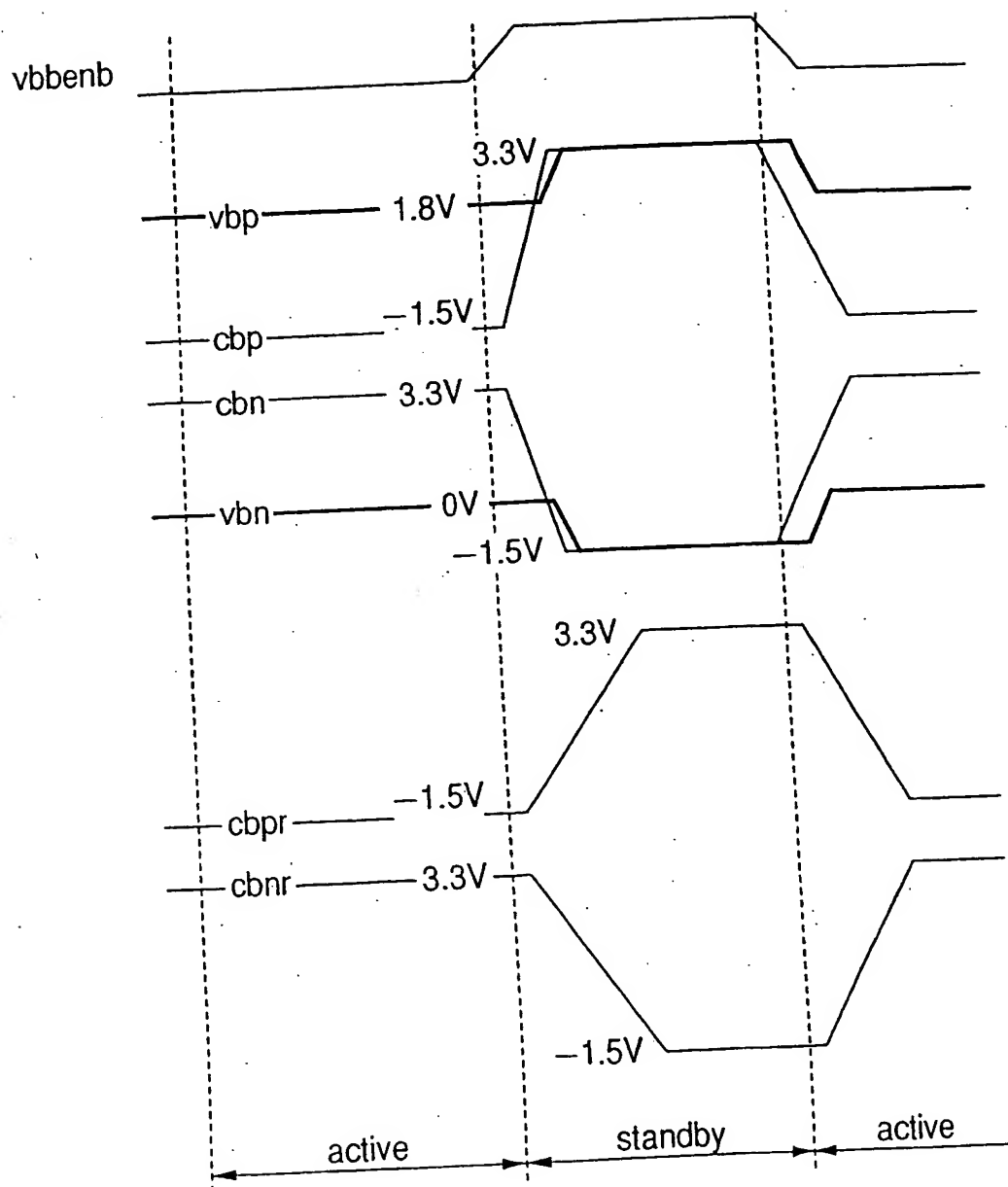
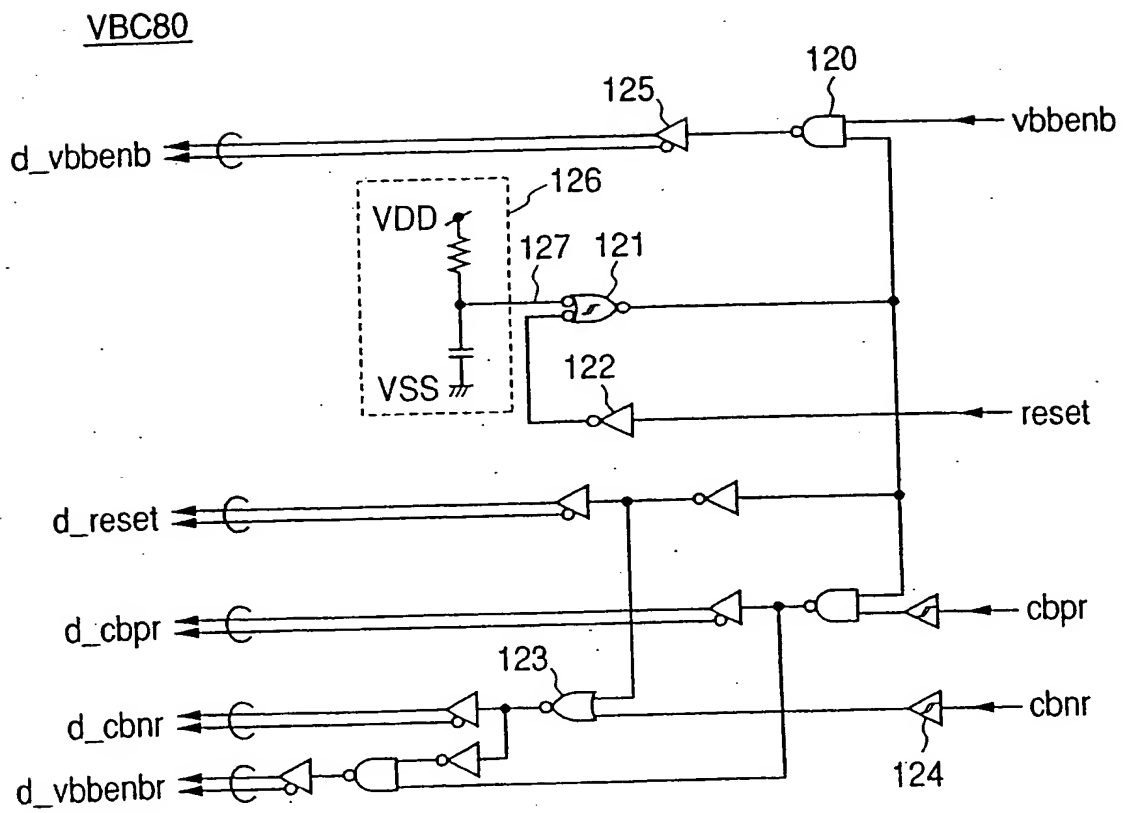
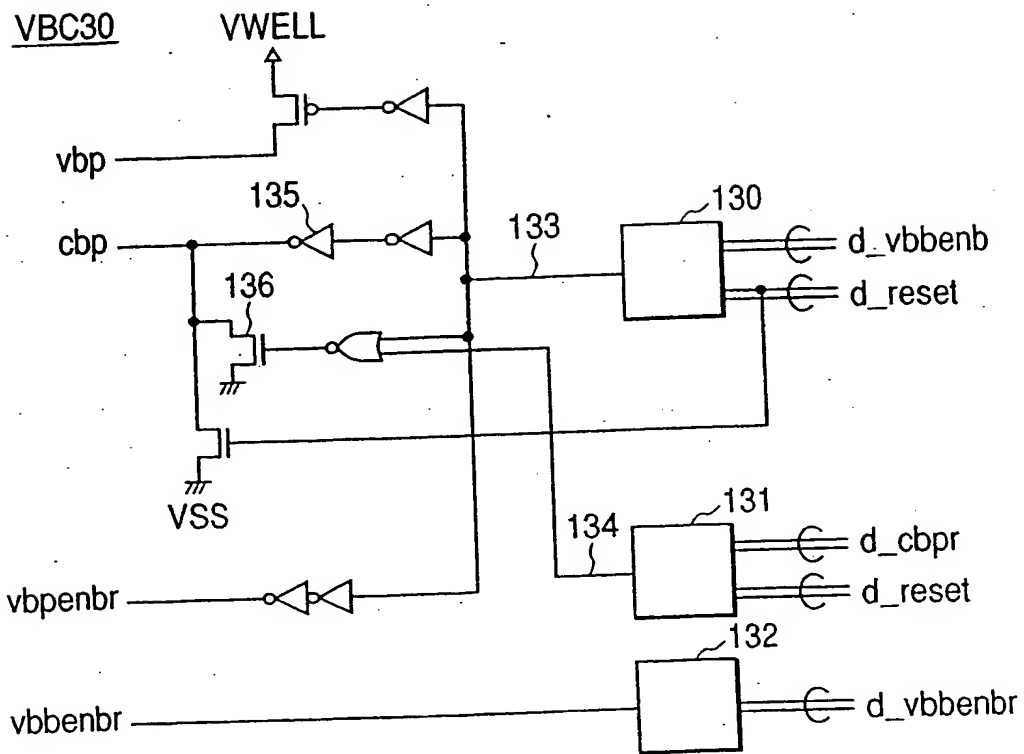
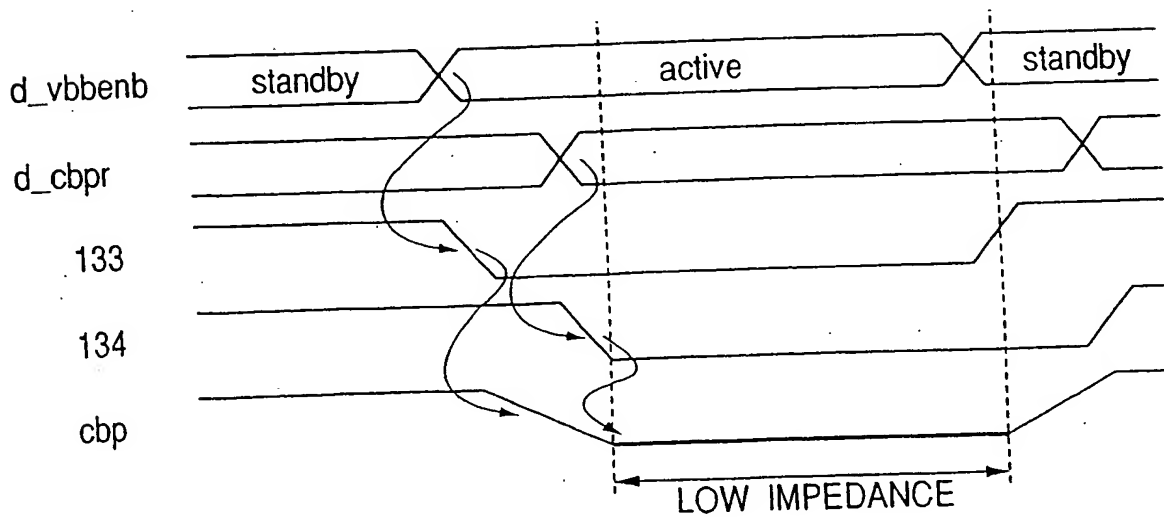
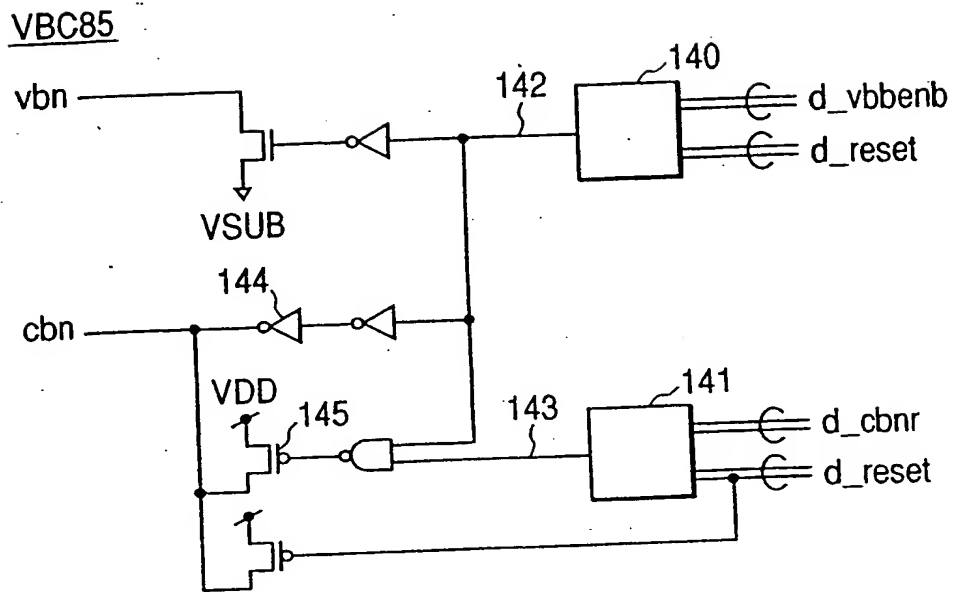
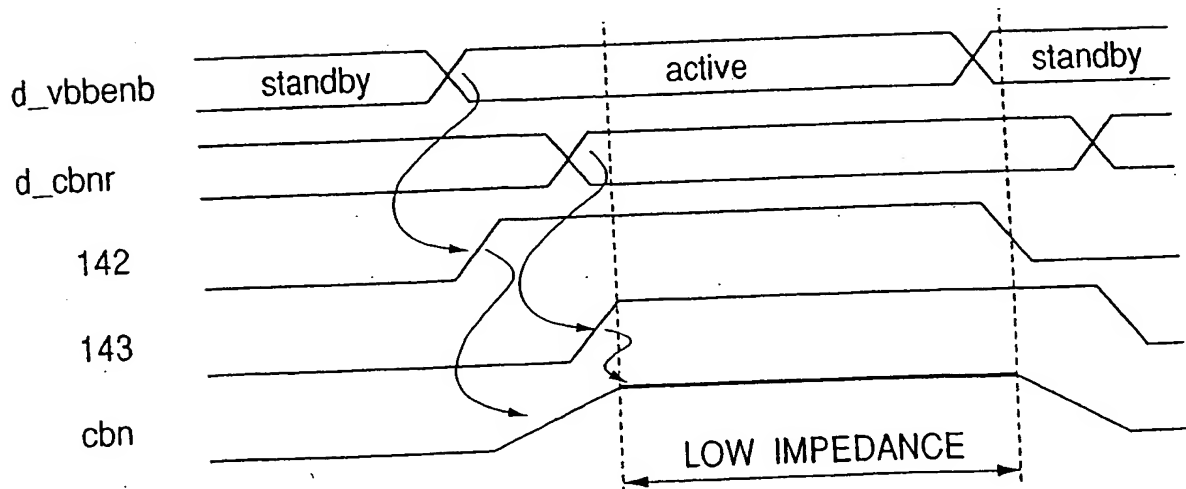
**FIG. 6**

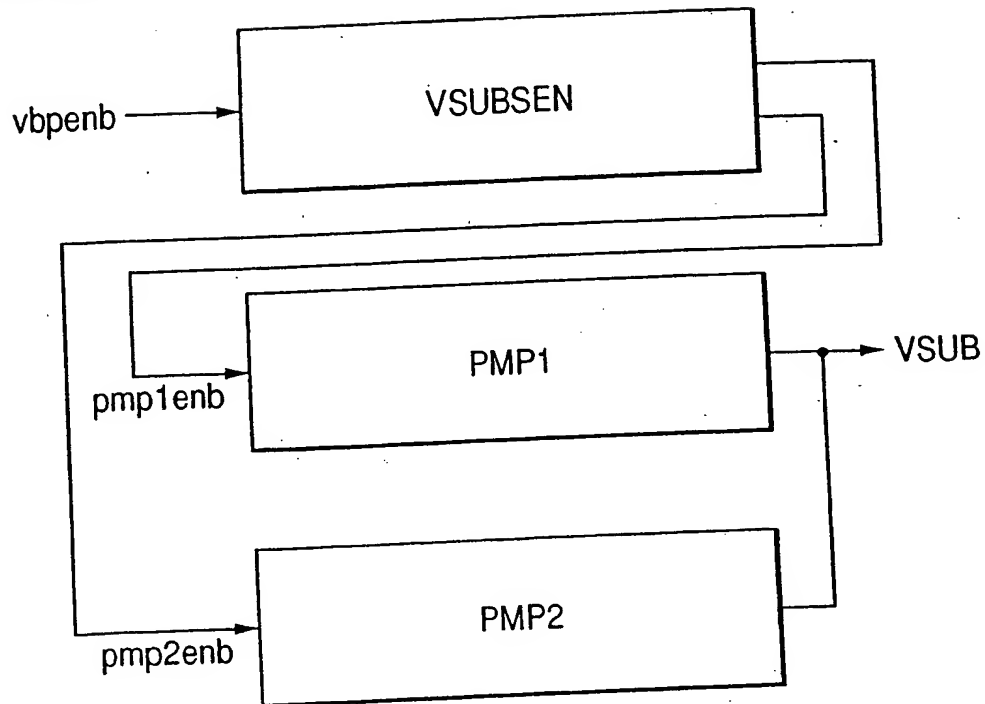
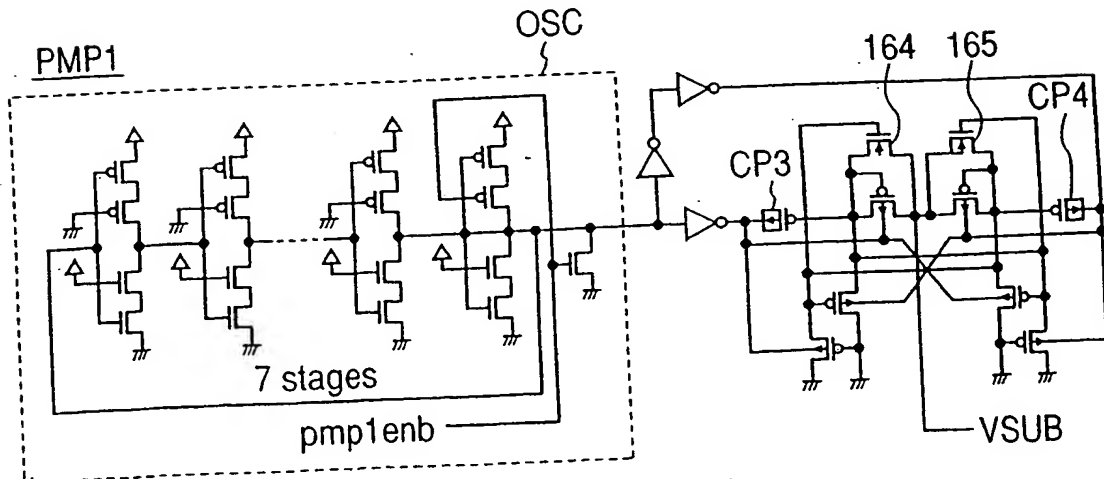
FIG. 7



**FIG. 8****FIG. 9**



**FIG. 10****FIG. 11**

**FIG. 12**VSUBGEN**FIG. 13**

**FIG. 14**

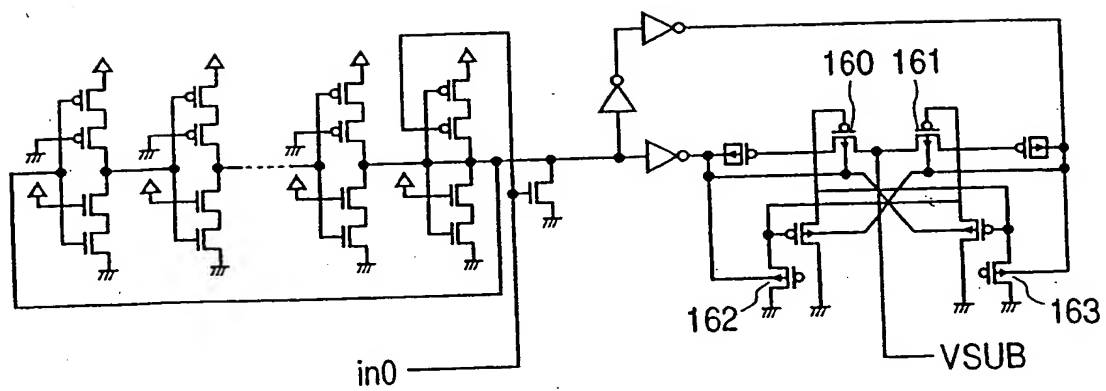
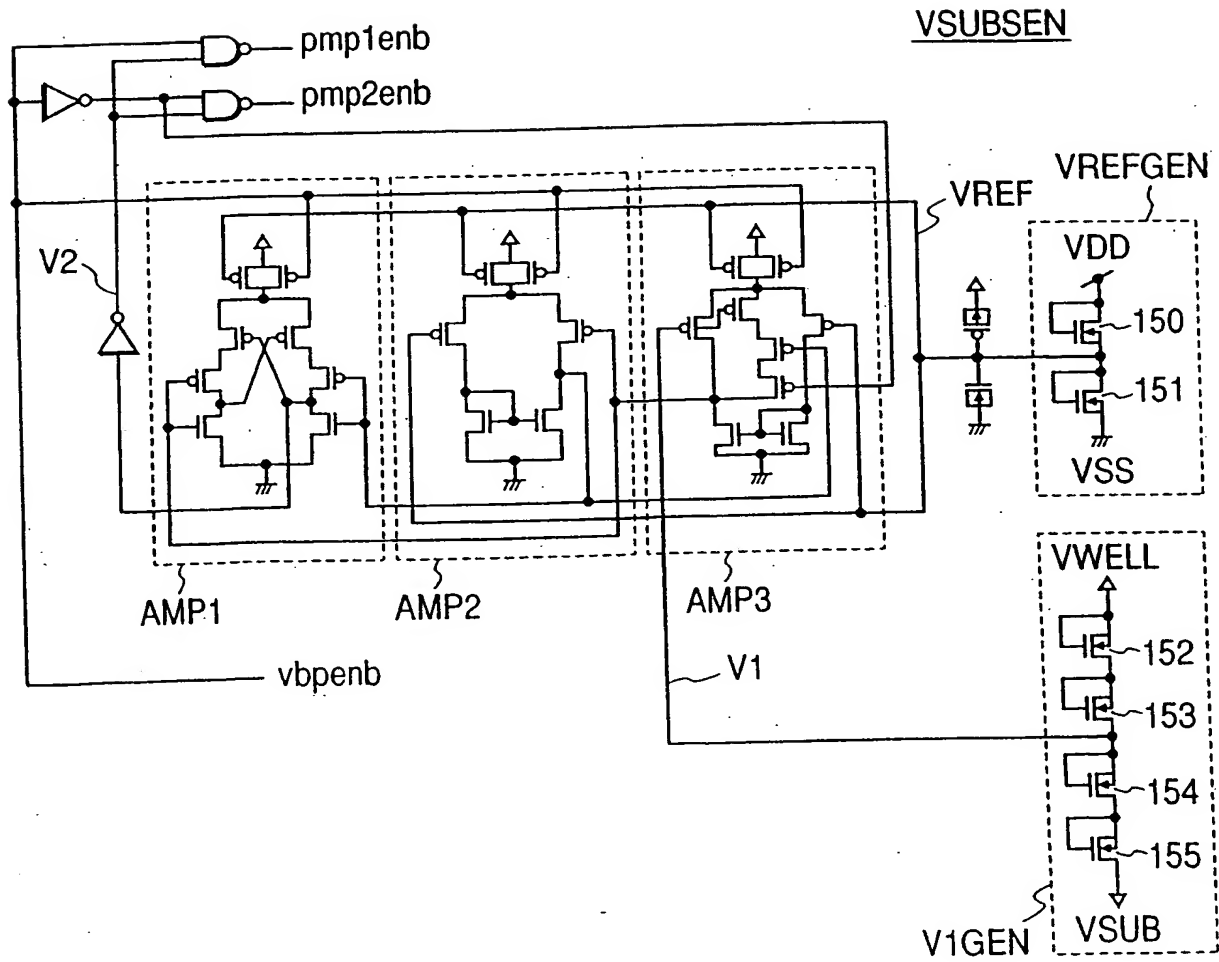


FIG. 15



**FIG. 16**

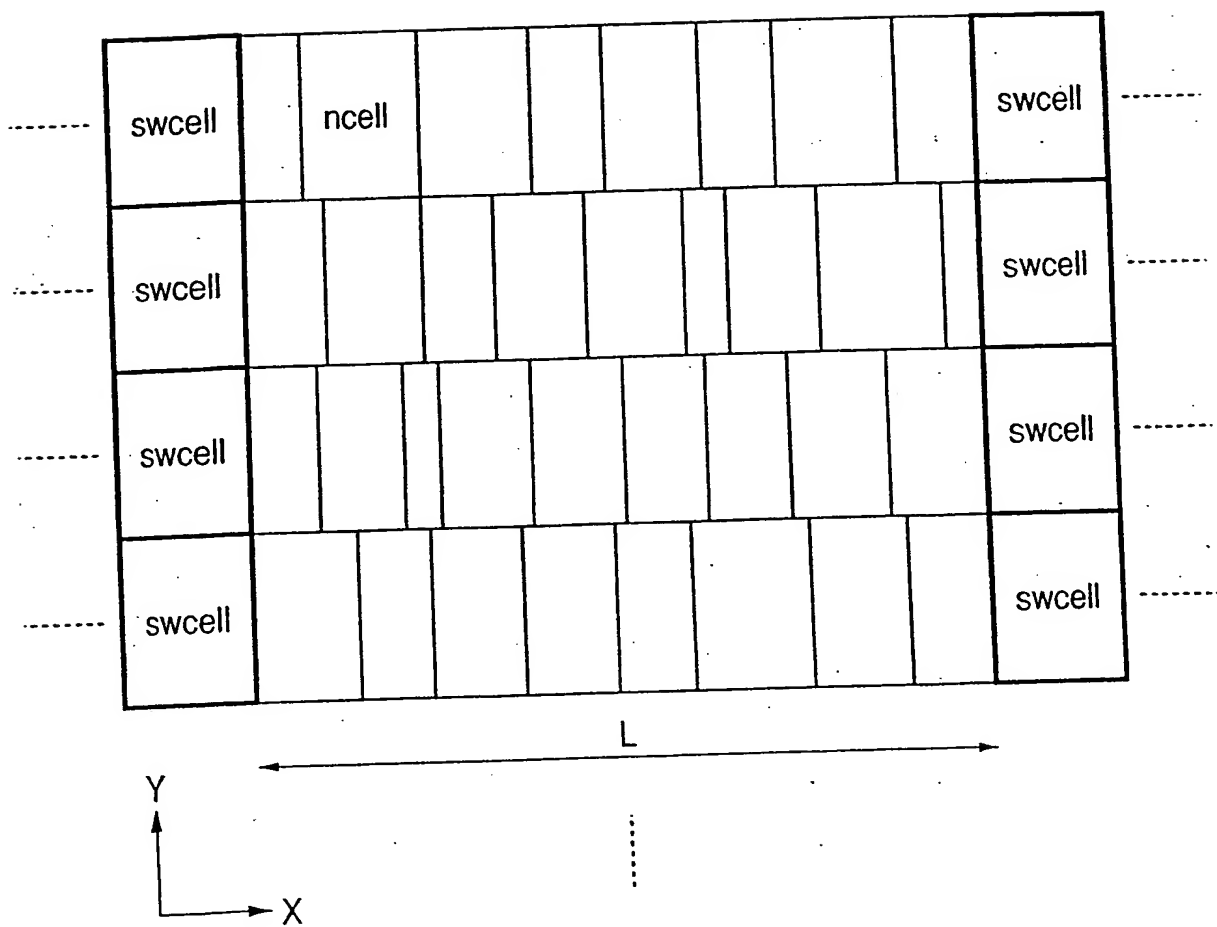
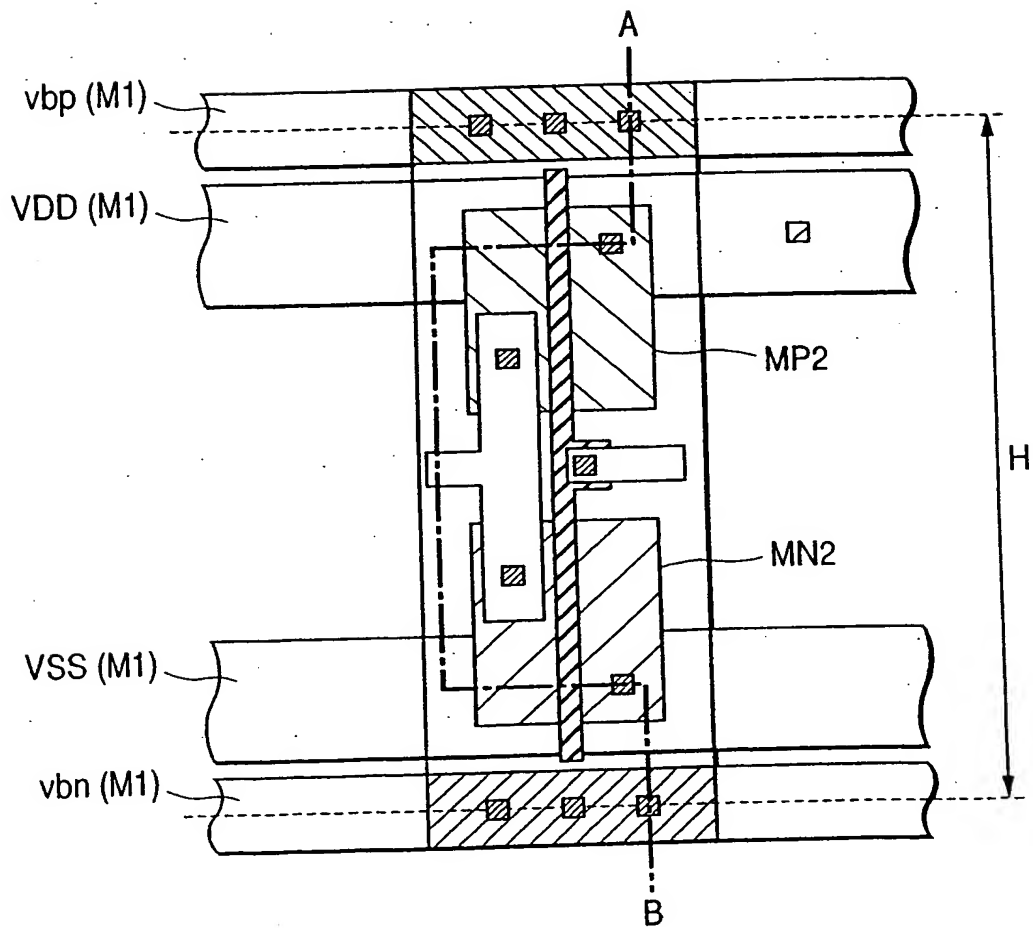




FIG. 17

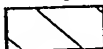


 GATE ELECTRODE

 M1

 CONTACT HOLE

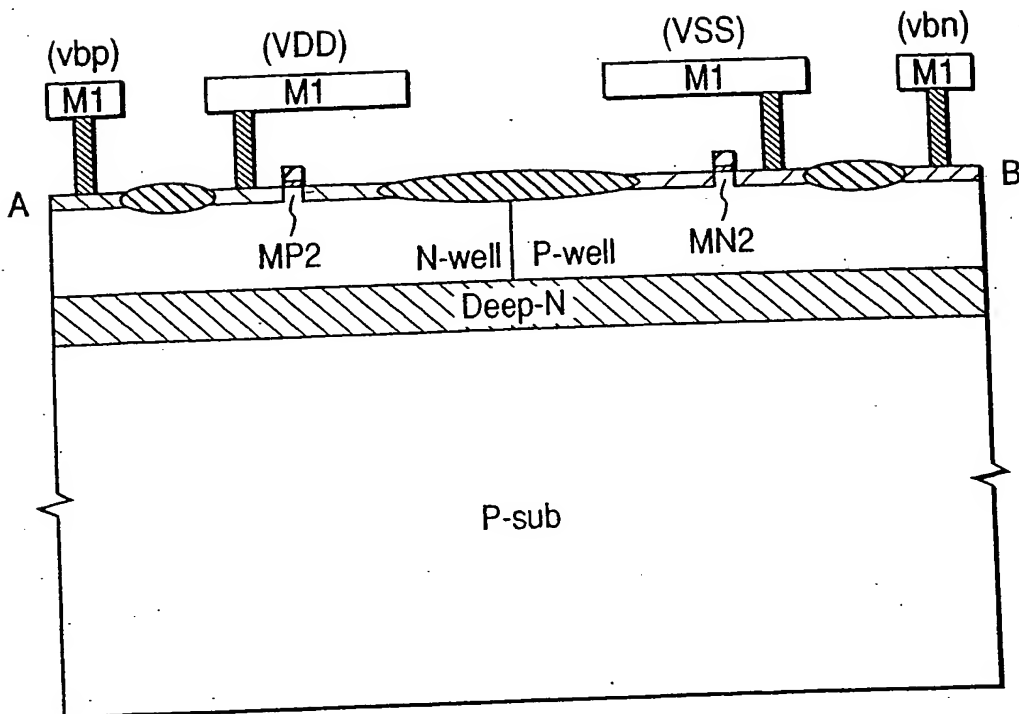
 NMOS ACTIVE AREA


 PMOS ACTIVE AREA


 SURFACE HIGH DENSITY N AREA FOR PMOS V<sub>BB</sub> SUPPLY

 SURFACE HIGH DENSITY P AREA FOR NMOS V<sub>BB</sub> SUPPLY


FIG. 18



 GATE OXIDIZATION FILM

 GATE ELECTRODE

 ISOLATION

 M1-M2 VIA HOLE

 NMOS ACTIVE AREA (N+)

 PMOS ACTIVE AREA (P+)

 SURFACE HIGH DENSITY N AREA FOR PMOS  $V_{BB}$  SUPPLY

 SURFACE HIGH DENSITY P AREA FOR NMOS  $V_{BB}$  SUPPLY

FIG. 19

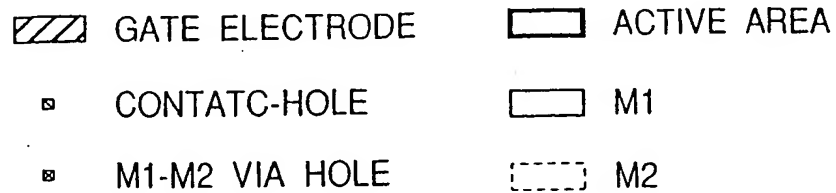
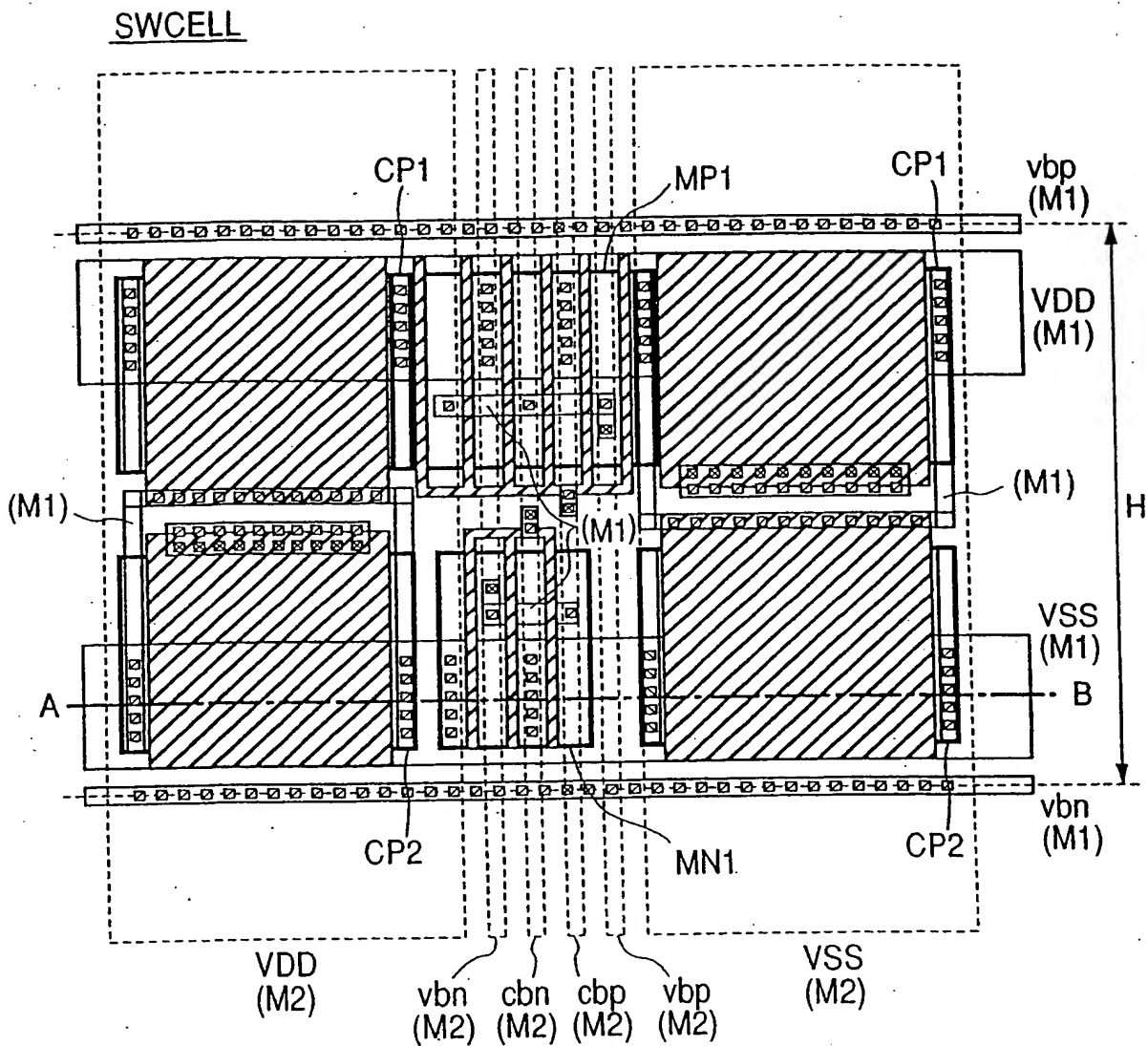
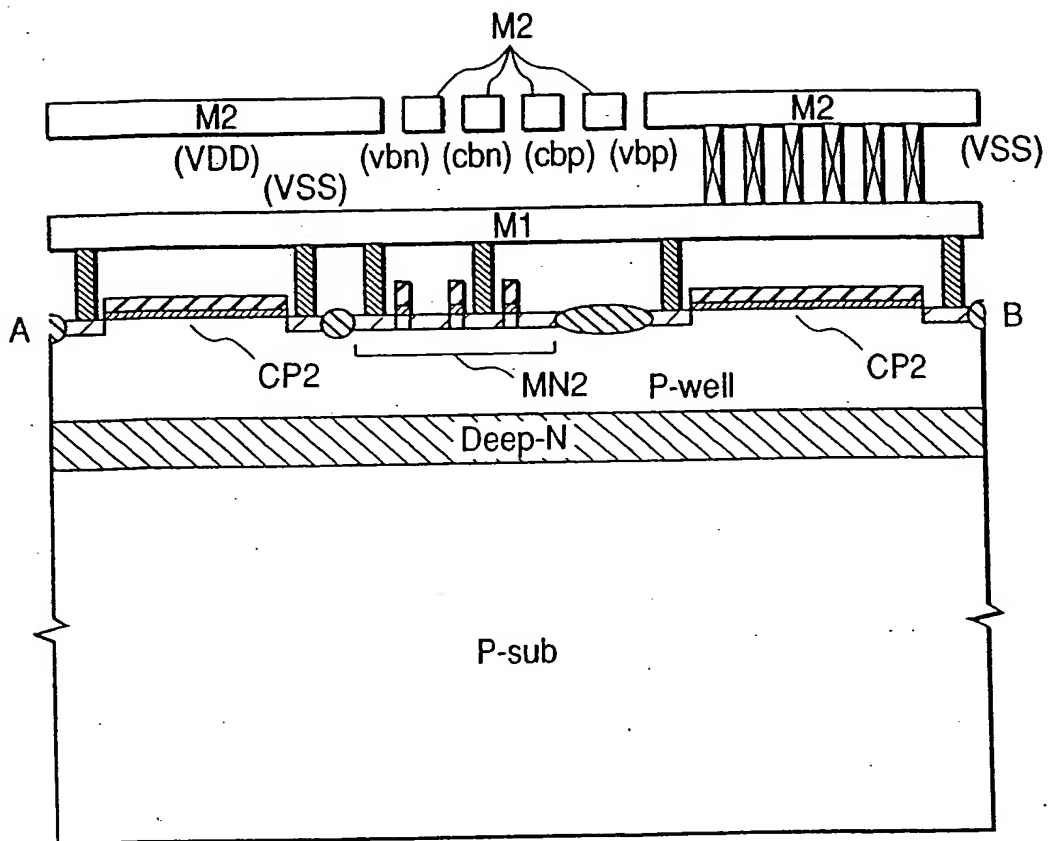







FIG. 20



 M1-M2 VIA HOLE

 CONTACT HOLE

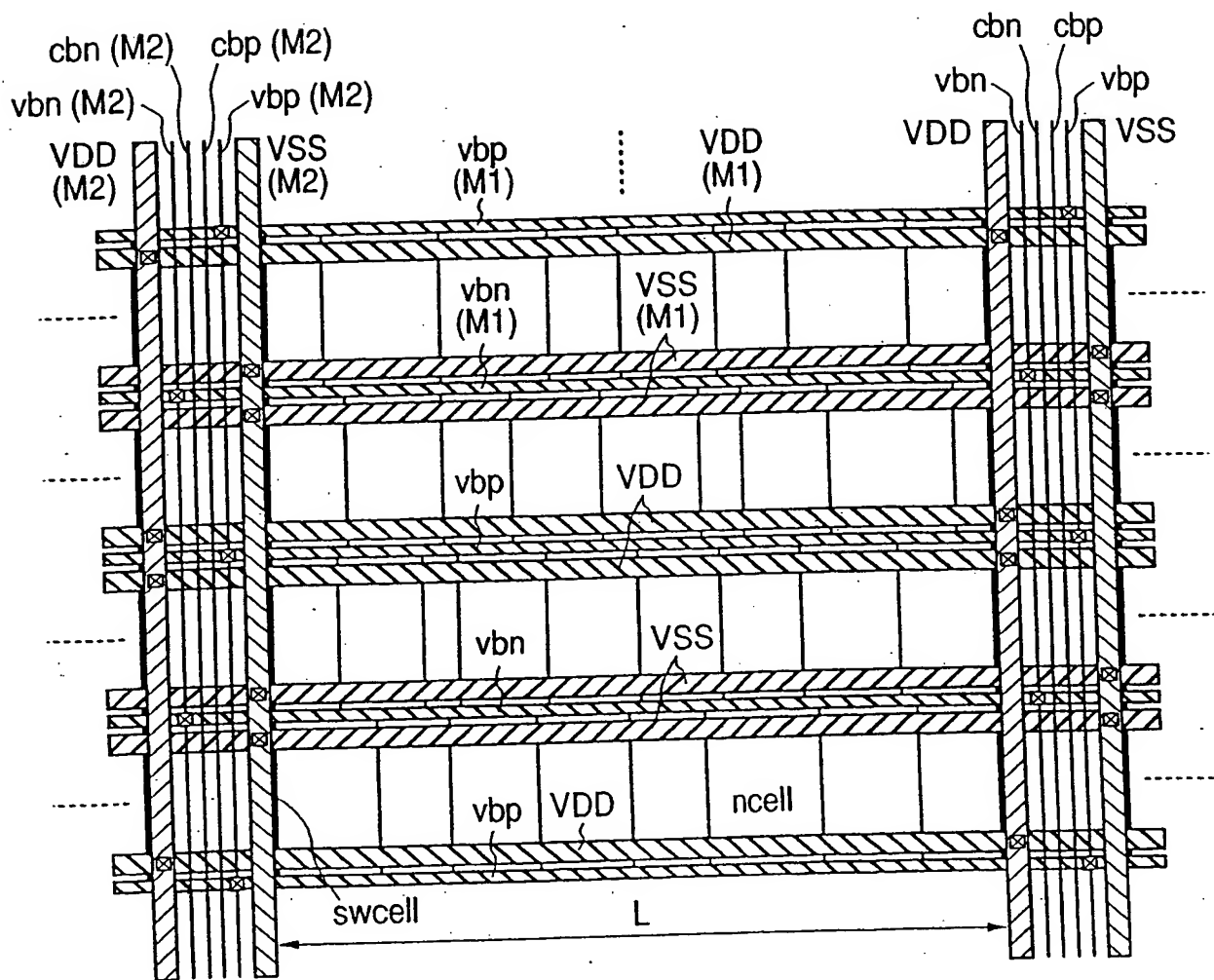
 GATE ELECTRODE

 GATE OXIDIZATION FILM

 ISOLATION

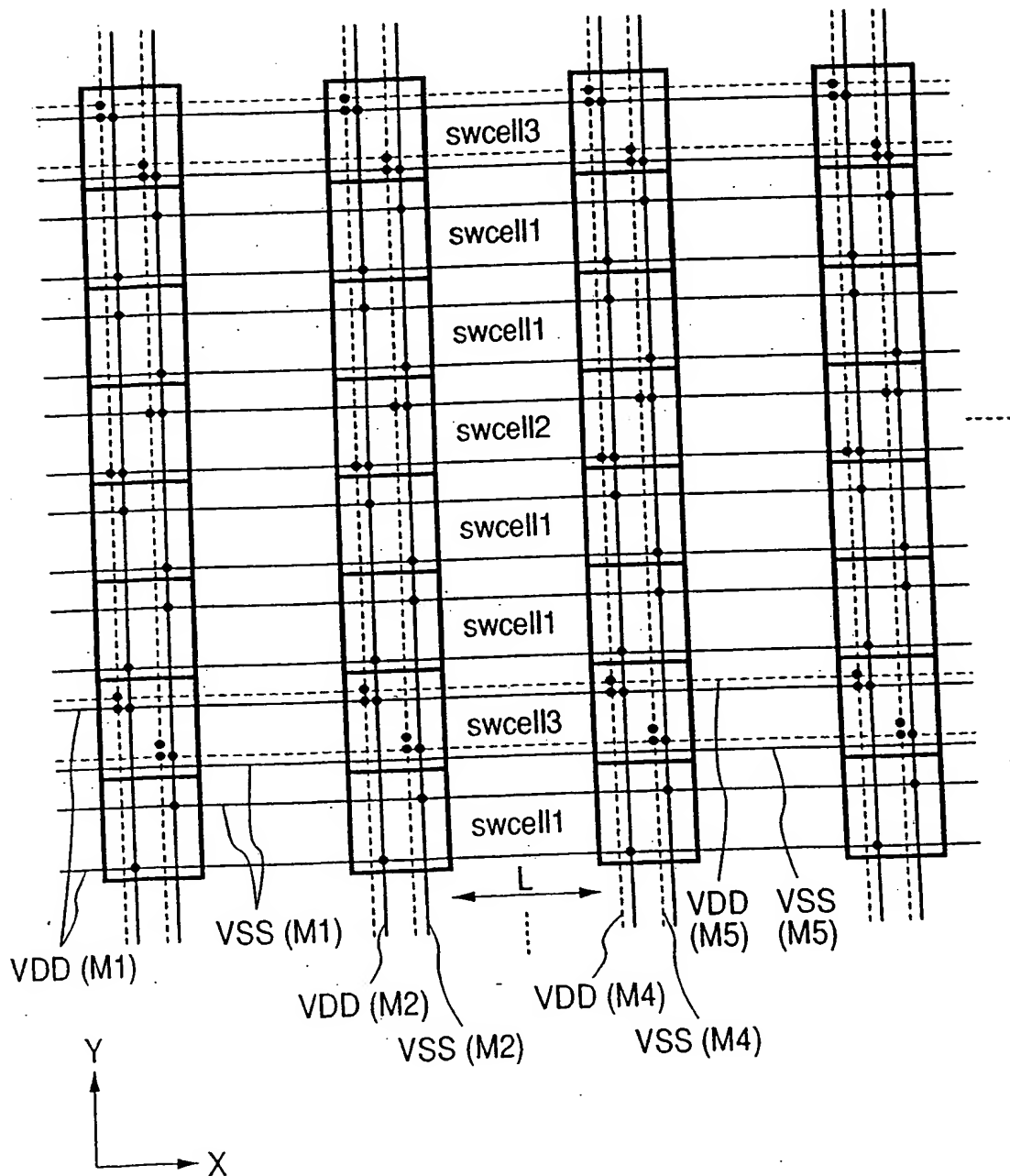
 N+ DIFFUSION FILM

FIG. 21



⊠ M1-M2 VIA HOLE

FIG. 22



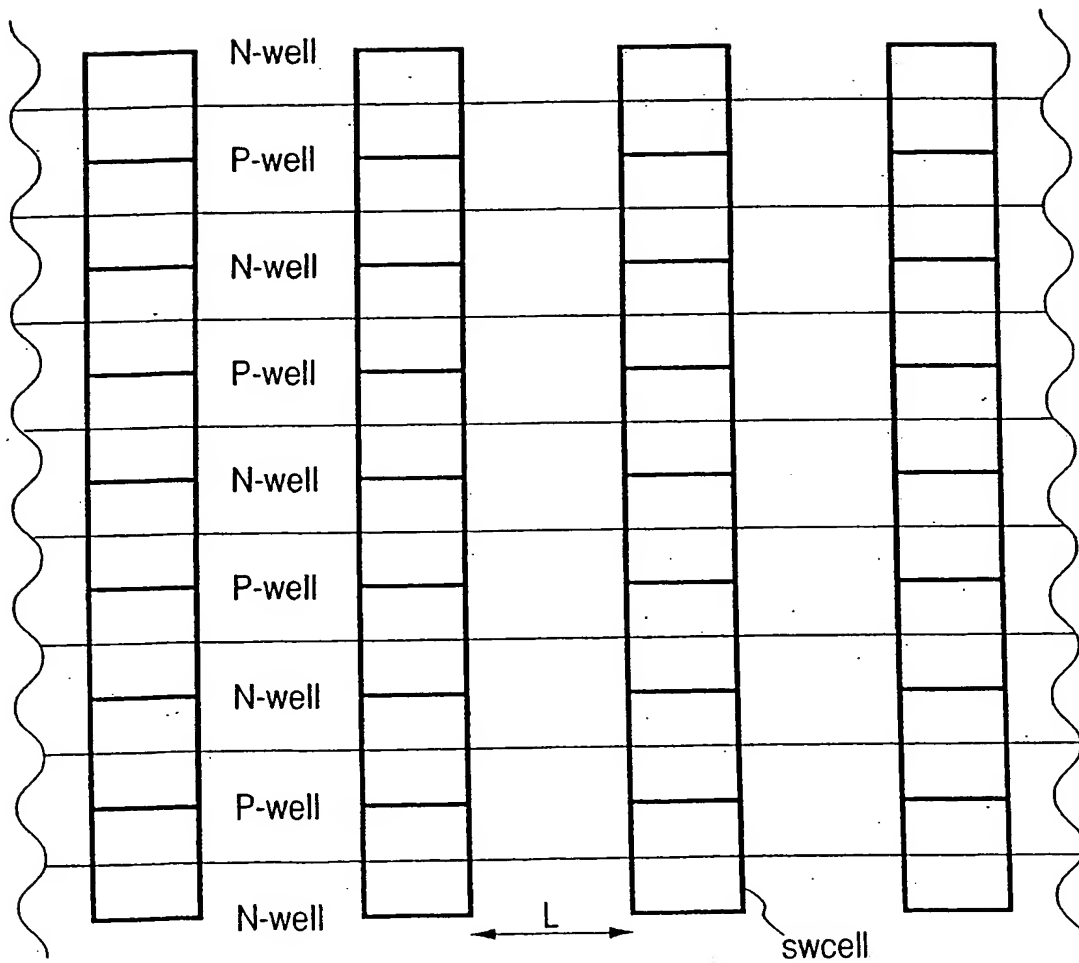
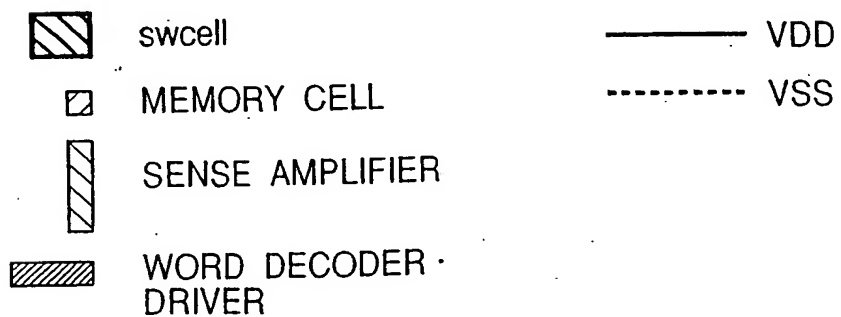
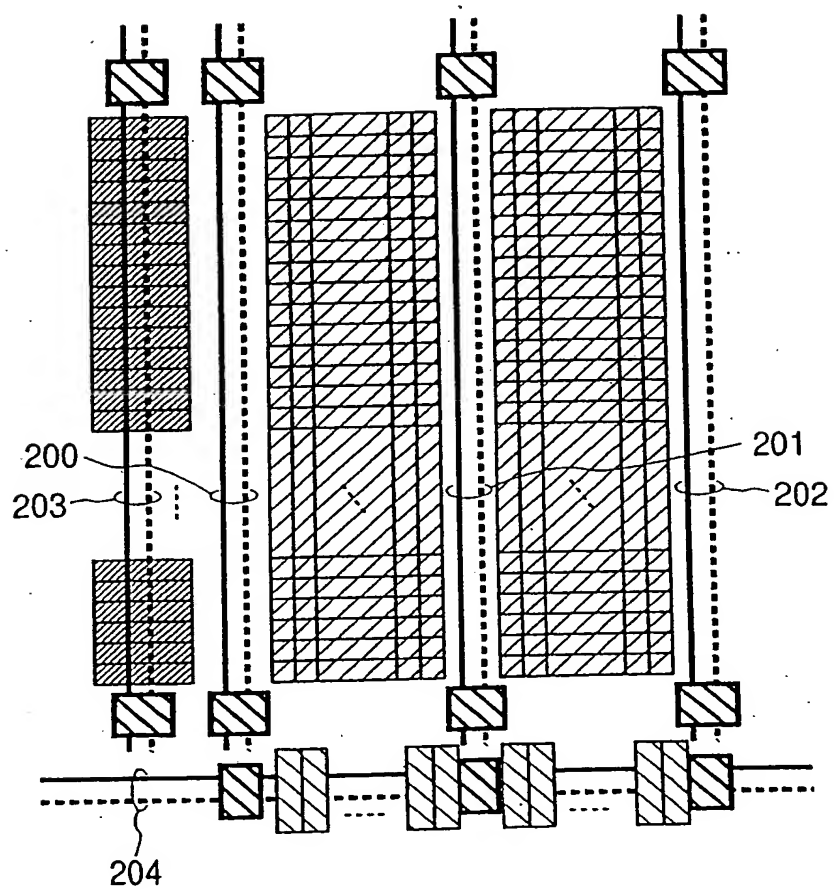
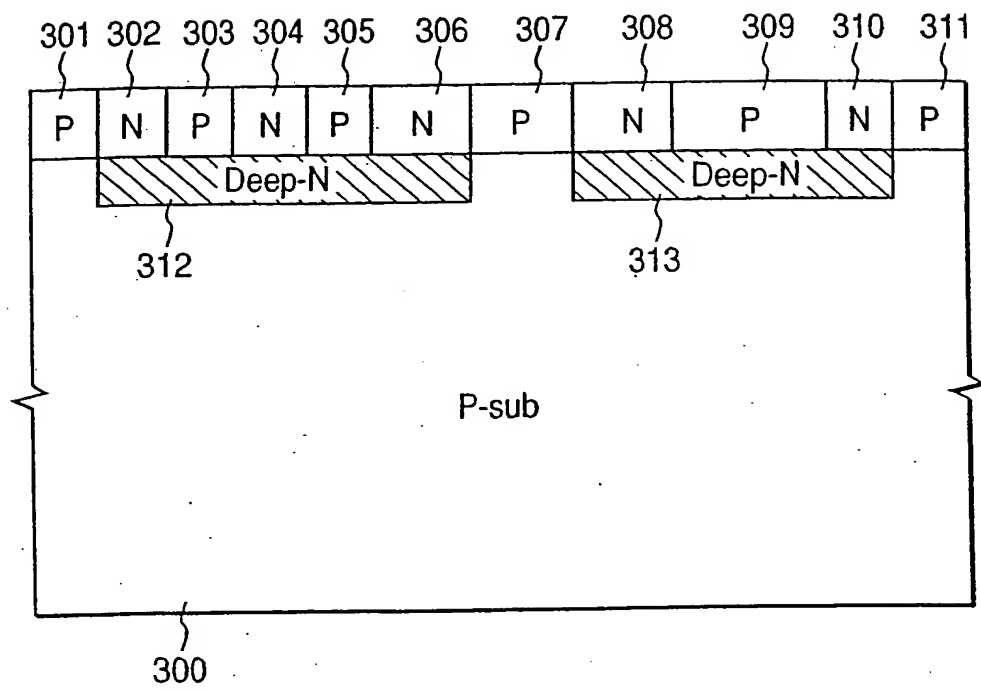
*FIG. 23*

FIG. 24



*FIG. 25*

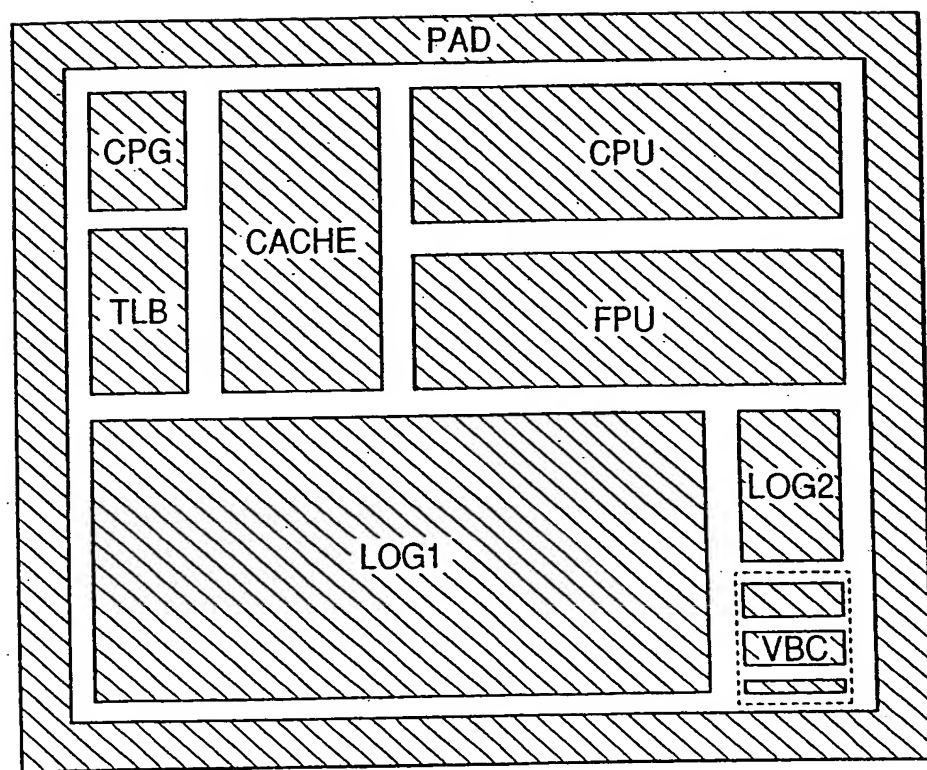
*FIG. 26*

FIG. 27

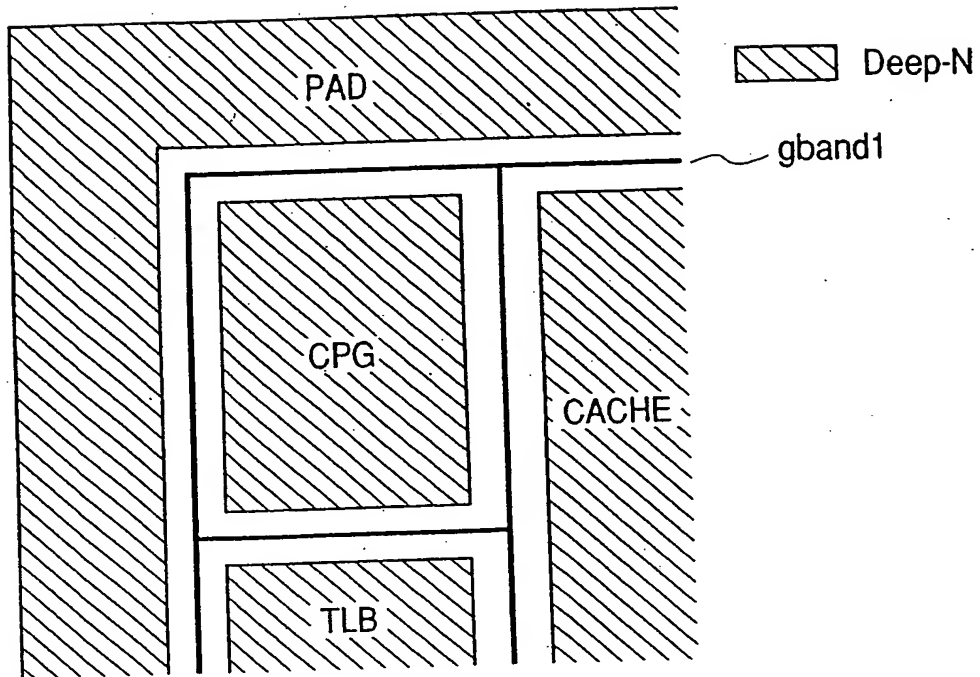


FIG. 28

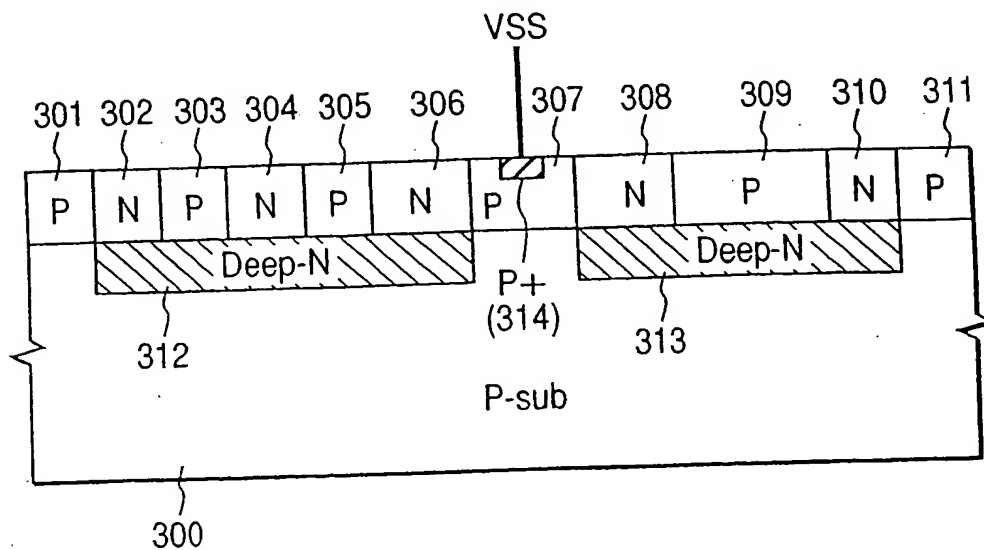




FIG. 29

